

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE	AGENT DOCKET NO. <b>ONX-107A</b>	SERIAL NO. <b>09/810,333</b>
<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (Use several sheets if necessary)	APPLICANT <b>Behrang Behin et al.</b>	
	FILING DATE <b>March 14, 2001</b>	GROUP <b>2831</b>

## U.S. PATENT DOCUMENTS

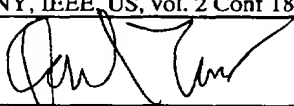
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<i>EW</i>	A	6	3	7	4	0	0	8	4/16/2002	Solgaard et al.	385	17	2/8/2001
<i>EW</i>	B	6	3	6	0	0	3	5	3/19/2002	Hurst et al.	385	16	6/2/2000
<i>EW</i>	C	6	3	2	9	7	3	7	12/11/2001	Jerman et al.	310	309	12/15/1999
	D	6	3	0	1	4	0	3	10/9/2001	Heanue et al.	385	18	12/15/1999
	E	6	2	9	6	7	7	9	10/2/2001	Clark et al.	216	66	2/22/1999
	F	6	2	5	7	0	6	2	7/10/2001	Rich	73	514.32	10/1/1999
	G	6	2	5	3	6	1	2	7/3/2001	Lemkin et al.	73	504.02	5/28/1999
	H	6	2	1	2	3	0	9	4/3/2001	Nguyen et al.	385	17	1/21/1999
	I	6	2	0	1	6	2	9	3/13/2001	McClelland et al.	359	223	8/26/1998
	J	6	1	3	7	9	4	1	10/24/2000	Robinson	385	140	9/3/1998
	K	6	1	3	4	2	0	7	10/17/2000	Jerman et al.	369	112	8/17/1998
	L	6	1	3	3	6	7	0	10/17/2000	Rodgers et al.	310	309	6/24/1999
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	O	6	0	0	0	2	8	0	12/14/1999	Miller et al.	73	105	3/23/1998
	P	5	9	6	9	8	4	8	10/19/1999	Lee et al.	359	298	7/3/1997
	Q	5	8	6	7	2	9	7	2/12/1999	Kiang et al.	359	198	2/7/1997
	R	5	5	6	5	6	2	5	10/15/1996	Howe et al.	73	514.16	12/1/1994
	S	5	5	4	3	9	5	6	8/6/1996	Nakagawa et al.	359	225	10/6/1993
	T	5	5	4	1	4	3	7	6/30/1996	Watanabe et al.	257	417	3/14/1995
	U	5	4	0	8	7	3	1	4/25/1995	Bergqvist et al.	29	25.41	11/5/1993
	V	4	4	1	3	7	6	6	11/8/1993	Webster	228	123	4/3/1981
	W	4	3	1	7	6	1	1	3/2/1982	Petersen	350	6.6	5/19/1980

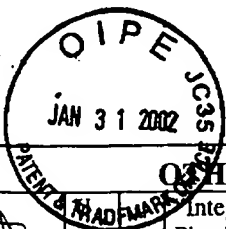
## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

## OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER <i>Paul J. Jones</i>	DATE CONSIDERED <i>11/14/04</i>
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<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (Use several sheets if necessary)										APPLICANT <b>Behrang Behin et al.</b>					
										FILING DATE <b>3/14/2001</b>		GROUP <b>2831</b>			
<b>U.S. PATENT DOCUMENTS</b>															
EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
<i>WT</i>	A	5	7	2	3	3	5	3	3/3/1998	Muenzel et al.	437	51	2/12/1996		
<i>WT</i>	B	5	7	2	6	0	7	3	3/10/1998	Zhang et al.	437	228	1/16/1996		
<i>WT</i>	C	5	7	5	3	9	1	1	5/19/1998	Yasuda et al.	250	306	1/16/1997		
<i>WT</i>	D	5	8	7	2	8	8	0	2/16/1999	Maynard	385	88	8/12/1996		
<i>WT</i>	E	6	3	3	0	1	0	2	12/11/2001	Daneman et al.	359	290	3/25/2000		
<i>WT</i>	F	5	9	5	9	7	6	0	9/28/1999	Yamada et al.	359	224	7/28/1998		
<b>FOREIGN PATENT DOCUMENTS</b>															
		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
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<i>WT</i>	G	0	9	0	7	0	7	6	A 2	4/7/1999	Europe	G01N	27/00		
<i>WT</i>	H	0	9	0	7	0	7	6	A 3	10/4/2000	Europe	H01J	37/63		
<i>WT</i>	I	0	9	1	1	9	5	2	A 2	4/28/1999	Europe	H02N	1/00		
<i>WT</i>	J	0	9	1	1	9	5	2	A 3	4/5/2000	Europe	H02N	1/00		
<i>WT</i>	K	1	9	7	5	7	1	8	A 1	7/1/1997	Germany	G02B	6/35		X
<i>WT</i>	L	1	9	6	4	4	9	1	A 8	4/30/1998	Germany	G02B	6/35	X	
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<i>WT</i>	N	2	7	3	2	4	6	7	A 1	4/10/1996	France	G01P	15/08		X
<b>OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>															
<i>WT</i>	O	"Electrostatic Comb Drive For Vertical Actuation" A.P. Lee et al., Proceedings of the SPIE, SPIE, Bellingham, VA, vol. 3224, Sept 29, 1997, pp 109-119													
<i>WT</i>	P	"Design, Fabrication, Position Sensing, And Control Of An Electrostatically-Driven Polysilicon Microactuator," P. Cheung et al, IEEE Transactions on Magnetics, vol. 32, no. 1, 1 Jan. 1996, pp 122-128													
<i>WT</i>	Q	"Optical Methods For Micromachine Monitoring And Feedback", F.M. Dickey et al., Sensors and Actuators, vol. 78, 1999, pp 220-235													
<i>WT</i>	R	"A High Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Selvakumar et al., Journal of Microelectromechanical Systems, IEEE Inc., New York, vol. 7, No. 2, June 1998, pp 192-200													
<i>WT</i>	S	"MEMS Fabrication of High Aspect Ratio Track-Following Micro Actuator for Hard Disk Drive Using Silicon On Insulator", B. H. Kim et al., Technical Digest of the IEEE International MEMS '99 Convergence. 12 <sup>th</sup> IEEE International Conference on Micro Electro Mechanical Systems. Orlando, FL, Jan 17-21, 1999, IEEE International Micro Electro Mechanical Systems Convergence, New York, NY, 1999, pp 53-56.													
<i>WT</i>	T	"Fabrication of Comb-Shaped Microactuator for Multi-Degrees-of-Freedom System", F. Fujikawa et al., Robotics, CIM and Automation, Emerging Technologies, San Diego, Nov. 9-13, 1992, Proceedings of the International Convergence on Industrial Electronics, Control, Instrumentation and Automation (IECON), New York, NY, IEEE, US, vol. 2 Conf 18, 9 November 1992, pp 990-995													
EXAMINER 										DATE CONSIDERED <b>1/14/04</b>					
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OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
W		Integrated Micro-Scanning Tunneling Microscope", Xu et al., Applied Physics Letters, American Institute of Physics, New York, vol. 67, No. 16, October 16, 1995 pp 2305-2307.
V		B. Behin et al., US Published Patent Application US 2001/004874 A1, Serial No. 09/751,660 "Two-Dimensional Gimbaled Scanning Actuator with Vertical Electrostatic Comb-Drive for Actuation and/or Sensing" Filed Dec 28, 2000 (ONX-105)
W		B. Behin et al., US Published Patent Application US-002001/050801-A1, Serial No. 09/810,336 "Biased Rotatable Combdribe Devices and Methods", Filed March 14, 2001, (ONX-106A)
X		B. Behin et al., US Patent Application Serial No. 09/809,994 "Biased Rotatable Combdribe Actuator Methods" Filed March 14, 2001 (ONX-106B)
Y		B. Behin et al., US Published Patent Application US-2001/0040419-A1, Serial No. 09/809,995 "Biased Rotatable Combdribe Sensor Methods", Filed March 14, 2001 (ONX-106C)
Z		B. Behin et al., US Published Patent Application US-2002/0051014-A1 Serial No. 09/810,326 "Optical Switch Employing Biased Rotatable Combdribe Devices and Methods", Filed March 14, 2001 (ONX-106D)
AA		B. Behin et al., US Patent Application US-2001/34938-A1, Serial No. 09/810,335 "Multi-Layer, Self-Aligned Vertical Combdribe Electrostatic Actuators And Fabrication Methods", Filed March 14, 2001 (ONX-107B)
AB		"Vertical Comb Array MicroActuators", A. Selvakumar et al., Proceedings of the Workshop on Micro Electrical Mechanical Systems (MEMS), Amsterdam, New York, Jan 29-Feb 2, 1995, IEEE Vol. Workshop 8 Jan. 29, 1995, pp 43-48, ISBN 0-7803-2504-4 ✓
AC		"Fabrication of a 3D Differential-Capacitive Acceleration Sensor by UV-LIGA", W. Qu et al., Sensors and Actuators 77 (1999), pp 14-20, Elsevier Science, 0924-4247/99/\$ 1/1999
AD		"Integrating SCREAM Micromachined Devices with Integrated Circuits", K.A. Shaw, N.C MacDonald, IEEE MEMS '96, San Diego, California 1996, IEEE Publication 0-7803-2985-6/96, pp 44-48, 1/1996
AE		"An electrostatically excited 2D-Micro-Scanning-Mirror with an in-plane configuration of the driving electrodes", H. Schenk et al., MEMS 2000, 13 <sup>th</sup> Int. Micro Electro Mechanical Systems Conf, Miyazaki, Japan, p. 473-478 (2000).
AF		"Damping of Micro Electrostatic Torsion Mirror Caused by Air-Film Viscosity", N. Uchida et al., No Date
AG		"Single Crystal Silicon (SCS) MicroMirror Arrays using Deep Silicon Etching and IR Alignment", C.S.B. Lee et al., No Date
EXAMINER		DATE CONSIDERED
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WT	A	5	9	9	8	9	0	6	12/7/1999	Jerman et al.	310	309	8/17/1998
WA	B	5	9	6	9	8	4	8	10/19/1999	Lee et al.	359	298	7/3/1997
CA	C	5	9	9	5	3	3	4	11/30/1999	Fan et al.	360	106	12/30/1997
WA	D	5	3	1	4	5	7	2	5/24/1994	Core et al.	156	643	4/22/1992
	E												
	F												
	G												
	H												
FOREIGN PATENT DOCUMENTS													
		DOCUMENT NUMBER						DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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	J												
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